## Supporting Information for

## Dendritic, Transferable, Strictly Monolayer MoS<sub>2</sub> Flakes Synthesized on

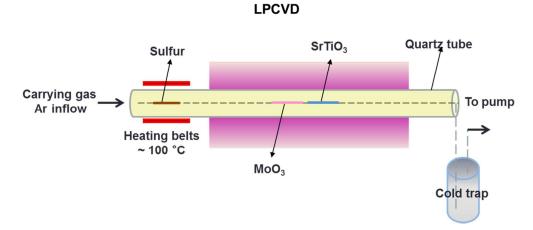
## SrTiO<sub>3</sub> Single Crystals for Efficient Electrocatalytic Applications

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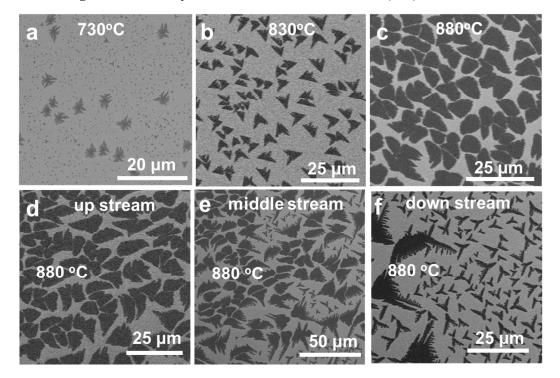
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1. Experiment setup of MoS<sub>2</sub> growth by LPCVD system.



**Figure S1** Schematic view of the utilized LPCVD system and the experimental setup for MoS<sub>2</sub> growth on STO(100) and STO(111) substrates.

In the LPCVD growth process, sulfur powder was mildly sublimated at ~100 °C and carried by Ar (50 sccm) gas flow, keeping the subsequent growth zone in a sulfur-rich atmosphere. The MoO<sub>3</sub> powder and STO substrates were heated to ~530 °C, ~880 °C, respectively. The tube furnace was pumped down to ~30 Pa to realize a LPCVD condition.

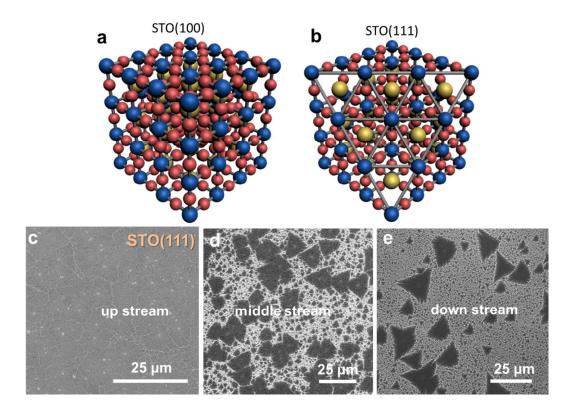


2. SEM images of LPCVD synthesized MoS<sub>2</sub> flakes on STO (100).

**Figure S2** Large scale SEM morphologies of LPCVD synthesized MoS<sub>2</sub> on STO (100). (a-c) SEM images of different shapes of MoS<sub>2</sub> flakes synthesized at various growth temperature of 730°C, 830°C and 880°C, respectively. (d-f) SEM morphologies of three MoS<sub>2</sub> samples with various coverage and distinct flake shape, synthesized under the same growth procedure (growth temperature 880°C) but with increased source-substrate distances ( $D_{ss}$ ) of 10.0 cm, 10.5cm and 11.0 cm, respectively.

Based on the above results, it can be inferred that, the growth temperature and the source-substrate distances ( $D_{ss}$ ) are significant parameters for modulating the morphology of MoS<sub>2</sub>. A high growth temperature usually results in compact MoS<sub>2</sub> flakes possessing rather sharp edges, as well as increased domain size. Moreover, a relative large precursor-substrate distance usually corresponds to rather small flake sizes and fractal flakes.

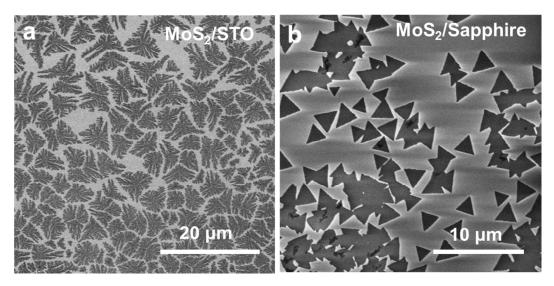
3. Crystal structures of two kind crystal faces of STO and the SEM images of synthesized MoS<sub>2</sub> on STO(111).



**Figure S3** LPCVD synthesis of MoS<sub>2</sub> on STO (111). (a-b) Crystal structures of STO (100) and STO (111), respectively. (c-e) Large scale SEM morphologies of MoS<sub>2</sub> samples synthesized on STO (111) under the same growth procedure (growth temperature 880°C) but with different source-substrate distances ( $D_{ss}$ ) of 10.0 cm, 10.5 cm and 11.0 cm, respectively, with the formation of nearly monolayer film (c) and submonolayer flakes (d,e).

It is also find that,  $MoS_2$  flakes can be synthesized on the single crystal substrate of STO (111). And the  $MoS_2$  flakes on STO (111) usually show more regular shapes than the growth on STO(100), as evidenced by the SEM images shown in Fig. S3d, e.

4. SEM morphologies of MoS<sub>2</sub> directly grown on STO and sapphire under the same growth batch.



**Figure S4** SEM morphologies of  $MoS_2$  directly grown on STO and sapphire under the same growth batch. (a, b)  $MoS_2$  on STO and on sapphire, respectively. The growth temperature of the synthesized samples was set at ~880°C, and the precursor substrate distance ( $D_{ss}$ ) was also set at a reasonable value.

Comparative SEM results indicate that, the generally synthesized  $MoS_2$  on STO (at a medium growth temperature) has a special fractal morphology, which is considered to be mediated by a relative strong interface interaction between  $MoS_2$  and STO, with regard to the system of  $MoS_2$  on sapphire.

5. AFM results of as-grown dendritic MoS<sub>2</sub> flakes.

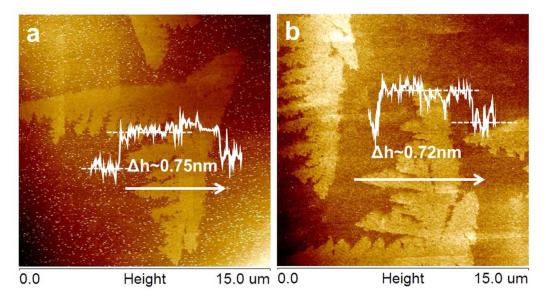


Figure S5 AFM images and corresponding height profiles along the white arrows of dendritic  $MoS_2$  flakes in both (a) and (b).

It is shown that, AFM results exhibit the morphologies of dendritic  $MoS_2$  flakes, mmeanwhile the height profiles manifest their monolayer feature.

6. Raman and PL measurments of bare STO substrates.

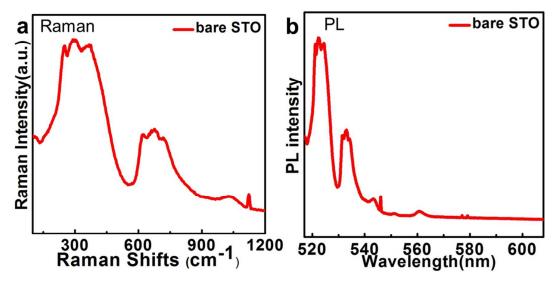


Figure S6 Raman (a) and PL (b) spectra of the bare STO substrate.

It is found that, from 300 cm<sup>-1</sup> to 750 cm<sup>-1</sup> (from 500 nm to 550 nm), the characteristic peaks of the bare STO substrate is very strong, and the Raman peaks of  $MoS_2$  cannot be identified.

7. SEM morphlogies of transferred MoS<sub>2</sub> flakes with dendritic edges onto SiO<sub>2</sub>/Si.

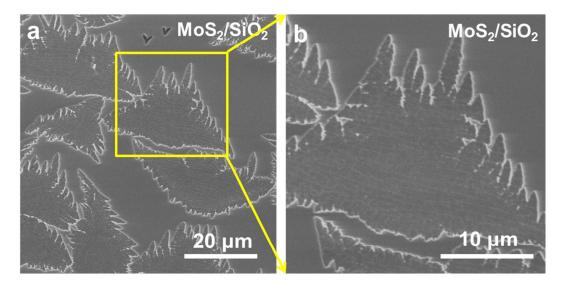


Figure S7 SEM images of  $MoS_2$  flakes after transference onto  $SiO_2/Si$  showing the maintenance of the dendritic edges of the flakes. (a) Large scale SEM image of transferred  $MoS_2$  on  $SiO_2/Si$  (b) Zoom in of the yellow square region in (a).

The SEM images show that, the  $MoS_2$  flakes can keep their original shapes even after the transfer process. Another interesting thing is that inside the flake, some white line shaped contrasts can be noticed and regarded as  $MoS_2$  wrinkles, probably arising from the duplication of the steps of the STO substrate. This fact provides side evidence of the perfect transfer process, considering that the transferred  $MoS_2$  flakes showing almost no broken, bending or folding.

8. SEM images of nearly complete monolayer MoS<sub>2</sub> transferred onto SiO<sub>2</sub>/Si.

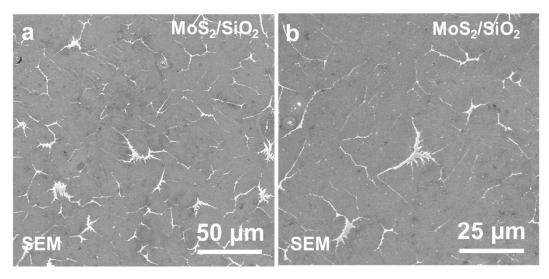
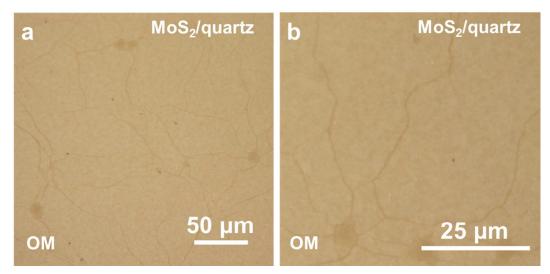


Figure S8 SEM images of nearly complete monolayer  $MoS_2$  after transference onto  $SiO_2/Si$  in both (a) and (b).

The SEM results of transferred  $MoS_2$  reveal that the complete monolayer  $MoS_2$  on STO can be transferred intact onto  $SiO_2/Si$ .

9. Optical photographs of monolayer MoS<sub>2</sub> transferred on quartz.



**Figure S9** Optical photographs of monolayer MoS<sub>2</sub> transferred on quartz. (a,b) Optical photographs of different scales MoS<sub>2</sub> on quartz.

The OM results of transferred  $MoS_2$  indicate that, the  $MoS_2$  on STO can be transferred intact onto quartz.

- a SEM 15µm 200 nm b 200 nm c c 5 nm 5 1/nm
- 10. High-resolution transmission electron microscopy (HRTEM) characterization of monolayer MoS<sub>2</sub> flakes.

**Figure S10** High-resolution transmission electron microscopy (HRTEM) characterization of monolayer  $MoS_2$  flakes. (a) Folded edge of the monolayer  $MoS_2$  with the SEM image of the sample as an inset. (b) HRTEM image and its FFT of monolayer  $MoS_2$ . (c) HRTEM images of an area consisting of monolayer (lower part) and stacked bilayer (upper part)  $MoS_2$ . (d) Corresponding SAED pattern of (c) showing two sets of diffraction spots.

The HRTEM results demonstrate the monolayer thickness and high crystal quality of the synthesized  $MoS_2$  on STO.

11. Nyquist plots of the three MoS<sub>2</sub> samples for the HER measurements.

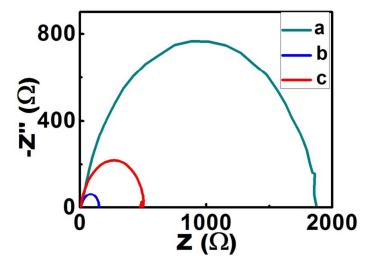


Figure S11 Nyquist plots of the three MoS<sub>2</sub> samples for the HER measurements.

The Nyquist plots show the charge-transfer resistance ( $R_{CT}$ ) of the three samples are 150  $\Omega$ , 400  $\Omega$  and 1750  $\Omega$ , respectively.